## Defect Inventory of CVT Grown TaS<sub>2</sub> Crystals

Dejia Kong<sup>1</sup>, Richard Peckham<sup>1</sup>, Zhiqiang Mao<sup>3</sup>, Seng Huat Lee<sup>3</sup>, Kory Burns<sup>2</sup>, Ian Harrison<sup>1</sup>, Petra Reinke<sup>2</sup>

1 Department of chemistry, University of Virginia

2 Department of Materials Science and Engineering, University of Virginia

3 Department of Materials Science and Engineering, Pennsylvania State University

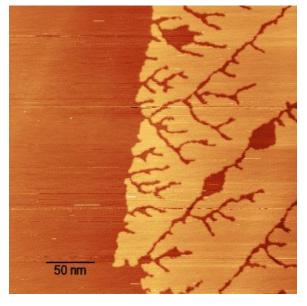


Figure 1. STM image of 2H-TaS<sub>2</sub> with the characteristic line surface defects on the right side of the image. (U<sub>bias</sub> = 1.0 V, I = 20 pA)

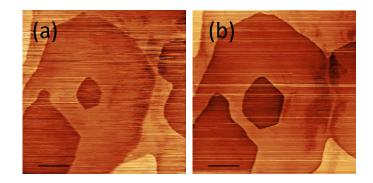


Figure 2. The STM with a vacancy island (v-island) starting imaging with (a) and ending with (b) after several hours of imaging. This illustrates the nanolithography process. On the right hand side of (b) an initially sub-surface line defect has been uncovered. (U<sub>bias</sub> = 1.5 V, I = 20 pA, scalebar = 150 nm)